



SLS:cmw 04/16/03 4641-58305 183571

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PATENT  
Attorney Reference Number 4641-58305

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re application of: NAKAYAMA et al.

Art Unit: 2878

Application No. 09/828,301

Filed: April 6, 2001

For: APPARATUS AND METHODS FOR  
MEASURING SURFACE PROFILES AND  
WAVEFRONT ABERRATIONS, AND  
LENS SYSTEMS COMPRISING SAME

Examiner: Kevin K. Pyo

Date: April 16, 2003

CERTIFICATE OF MAILING

I hereby certify that this paper and the documents referred to as being attached or enclosed herewith are being deposited with the United States Postal Service on April 16, 2003 as First Class Mail in an envelope addressed to: BOX NON-FEE AMENDMENT, COMMISSIONER FOR PATENTS, WASHINGTON, D.C. 20231.

*Donald L. Stephens*  
Attorney for Applicant

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TRANSMITTAL LETTER

BOX NON-FEE AMENDMENT  
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Enclosed is an Amendment for the above application.

- No additional fee is required.
- Please charge any additional fees that may be required in connection with filing this amendment and any extension of time, or credit any overpayment, to Deposit Account No. 02-4550. A copy of this sheet is enclosed.
- A Marked-up Version of Amended Claims Pursuant to 37 C.F.R. §§ 1.121(b)-(c) is attached.
- Please return the enclosed postcard to confirm that the items listed above have been received.

Respectfully submitted,

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By

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cc: Docketing



DLS:cmw 04/16/03 183550

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AMENDMENT AND RESPONSE TO RESTRICTION

This paper is submitted in reply to the Restriction Requirement, dated March 25, 2003.

Please amend the subject application as follows:

04/24/2003 A In the claims 024550 09828301

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Please amend claims 1, 4, 5, and 7 as follows:

1. (Amended) An apparatus for measuring an optical characteristic of a target object, comprising:

a light source configured to produce a light flux;  
a light-flux optical system situated relative to the light source and the target object and configured to (i) produce from the light flux a measurement-light flux and a reference-light flux, (ii) direct the measurement-light flux to the target object so as to cause the measurement-light flux to interact with the target object and thus acquire a wavefront profile corresponding to the optical characteristic of the target object, (iii) provide the reference-light flux with a standard wavefront, and (iv) establish an interference between the reference-light flux and the measurement-light flux from the target object;

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